

Editor's Comment:

I carefully reviewed the revised manuscript entitled "**Characterisation of Defects Induced by Ion-implantation Processing of P+N Shallow Junction Devices**", when I go through the reviewers comments and authors reply, I noticed some improvement in the revised manuscript and two of the reviewers already given high marks to the manuscript, From editorial point of view, the final decision of this manuscript is **accept.**

Editor's Details:

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